

Gaseous detectors Task 13.4.7

MPGD detectors to industry

Preparation for large series production: standard production protocols of optimized MPPGD components to ease technology dissemination

(project leader : Fabien Jeanneau)

Gaseous detectors Task 13.4.2

Resistive anode Micromegas

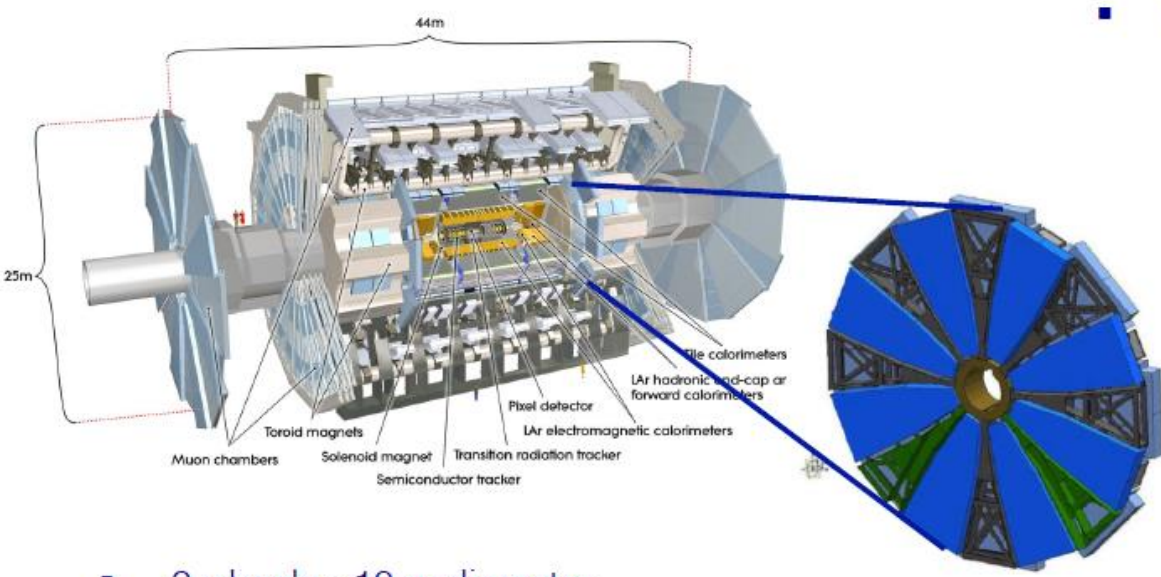
Preparation for large series production: procedures and tools for large series resistive micromegas anodes

(project leader : Stephan Aune)

These two tasks are very interrelated. The Resistive Anode task has a deliverable now (D13.7 for M24)

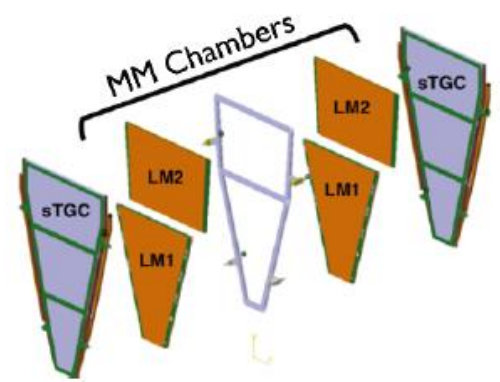
The ATLAS New Small Wheel project

- Upgrade of the innermost forward detector wheels of the ATLAS muon system during LHC Long Shutdown 2 (2019/2020)



- NSW requirements
 - Spatial resolution up to 32° track inclination
 - 100 μm in precision coordinate (η)
 - $\sim\text{mm}$ in azimuthal coordinate (ϕ)
 - 1 mrad angular resolution (from HL-LHC L1 trigger requirement)
 - Bunch crossing identification
 - Efficiency $> 98\%$
 - Rate capability $> 15 \text{ kHz/cm}^2$

- 2 wheels $\sim 10 \text{ m}$ diameter
- 2 detector technologies both with triggering and tracking capabilities:
 - Micromegas: primary tracking detector
 - sTGC: primary trigger detector
- High redundancy: 8 sTGC and 8 MM layers arranged in quadruplets

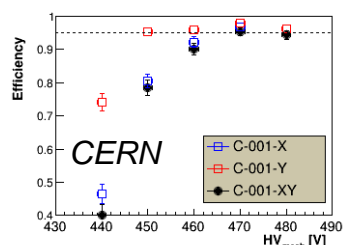
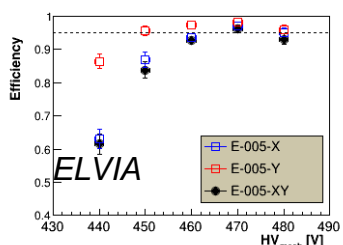
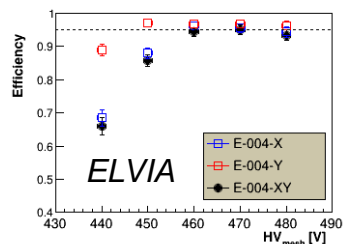
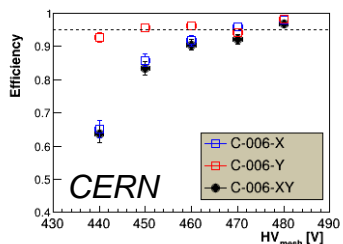
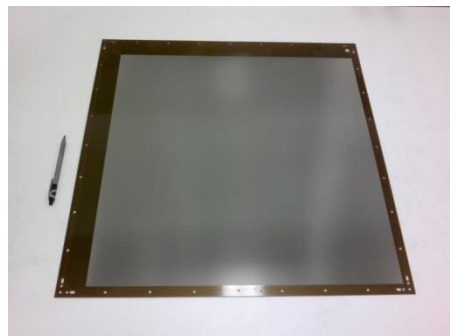
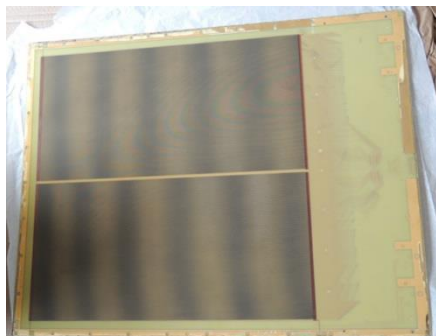


→ Know-how transfer to ELVIA-PCB since several years
LARGE MICROMEASUREMENTS FOR NSW (ATLAS MUON CHAMBERS)

2013

End 2015

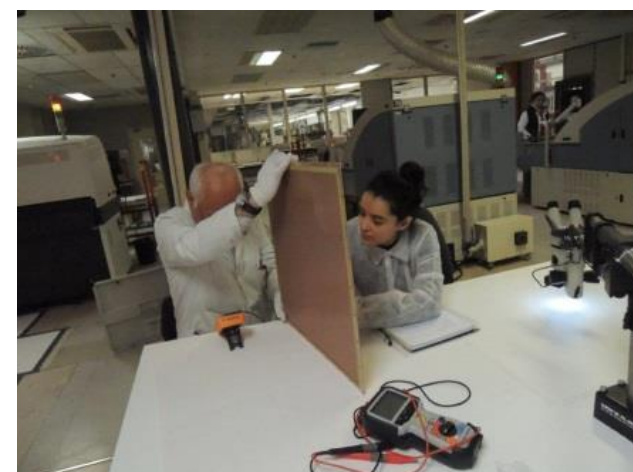
March 2016



First operational
prototypes in 2015
Now NSW under
construction

Compatible performance
between Cern and Elvia
prototypes

Transfer in progress

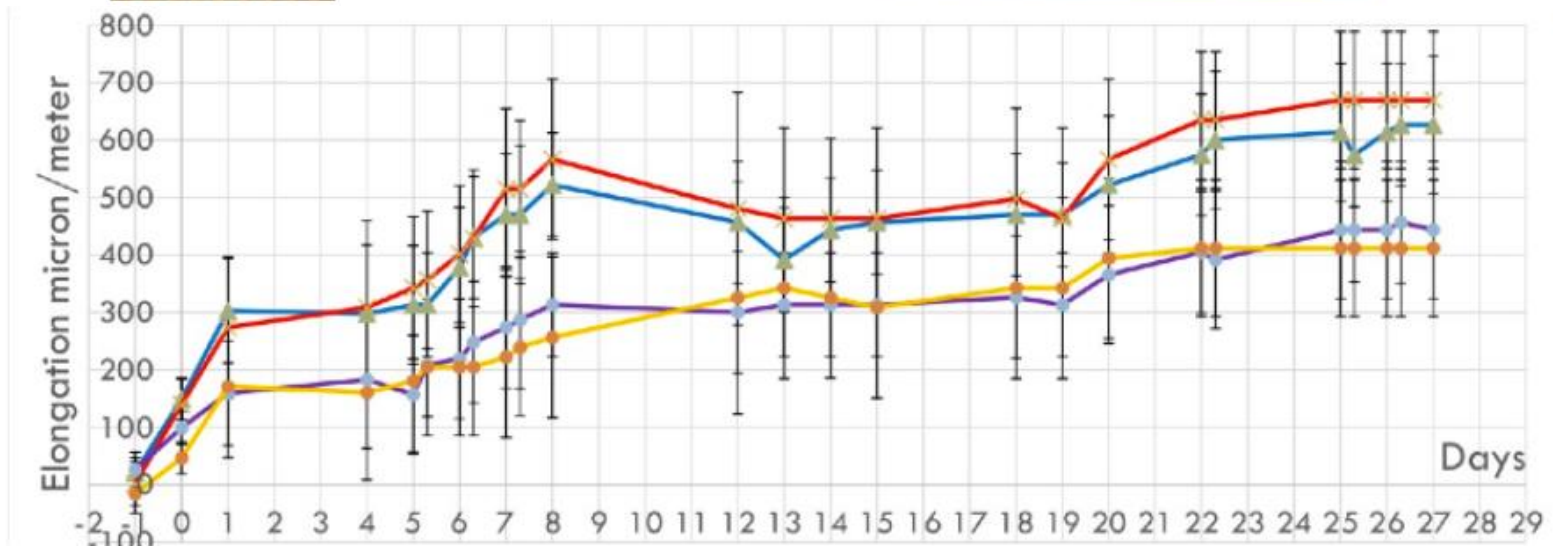


- Enclosures and bubbles



Great improvement:

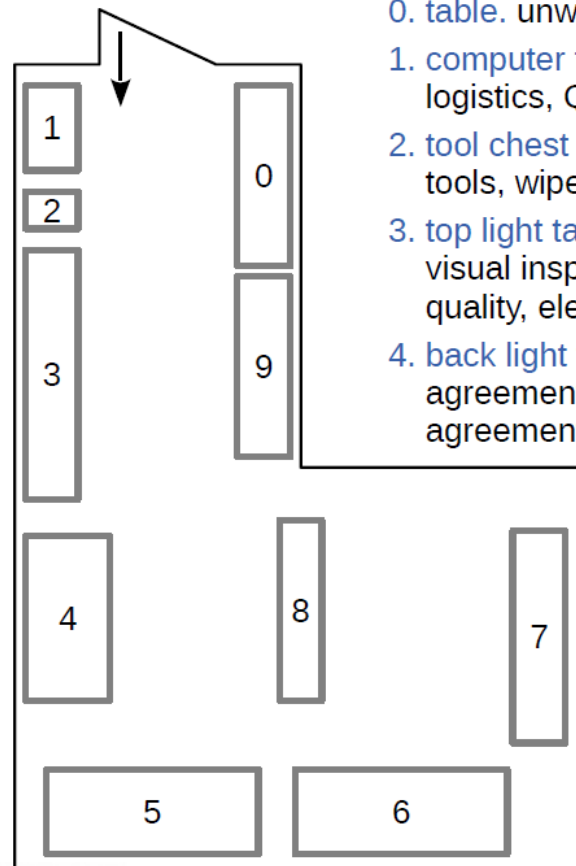
- Technological transfer
- Procedure and work-flow optimization
- Cleanliness during gluing



- Confirmed expansion as mostly related to humidity level (small effect of T)
- Saturation at $\sim +450\mu\text{m}/\text{m}$

→ Now ELTOS and ELVIA are doing the production and CERN is doing the QC

Quality Control Workflow – QC Lab in 188



- 0. table. unwrapping
- 1. computer table
logistics, QC form setup, check of supplier report, coffee machine
- 2. tool chest
tools, wipes, gloves & chemicals
- 3. top light table
visual inspection, pairing of res. foil and board (log db), etching quality, electrical tests
- 4. back light table
agreement holes & Cu pattern, edge precision & straightness, agreement resistive & Cu pattern, pillar pattern
- 5. rasmask granite table
absolute dimensions & shape $O(30\mu\text{m})$
- 6. granite table
pillar height measurement
- 7. table
resistivity mapping
- 8. shelf
final storage
- 9. table
strip capacitance measurement



Logistics of Readout PCBs

material stored at CERN and distributed as needed (FR4, resistive foils, coverlay, silver paste)

Elvia 1296 boards (LM1, LM2, SM2 Eta)

Eltos 884 boards (SM1, SM2 Stereo)

→ regular shipping to CERN O(50) boards

- counting & registration of all boards
- **in depth quality control of all boards**
 - dimensions & mechanical accuracy
 - electric integrity & HV stability
 - long-term stability
- acceptance/rejection decision
- board quality summary for each individual board
- drilling of precision holes

produced Dec. 2016 to Feb. 2018

telephone calls every second day

visits every four weeks

central logistics database

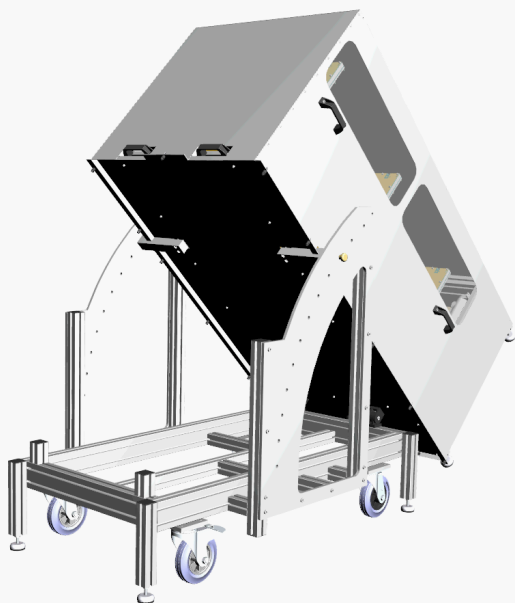
up to 2h per board

CERN RO PCB QC database

aggregation & packaging

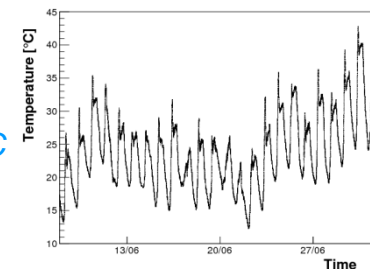
ship to constructions sites or prepare for pick-up

1st muon telescope with multiplexed Micromegas



→ 1st use of MM tracker outside

- *Temperatures fluctuations from 11 to 43°C*
- *Online feedback on T (P)*



→ FEU from Clas12



→ Self-trigger mode

→ Miniaturized CAEN HV modules

→ Nano-PC (Hummingboard)

- *Set & monitor HV*
- *Acquisition & storage*



→ Compact electronic system



→ 30 W of consumption

→ 3.5 months of data taking

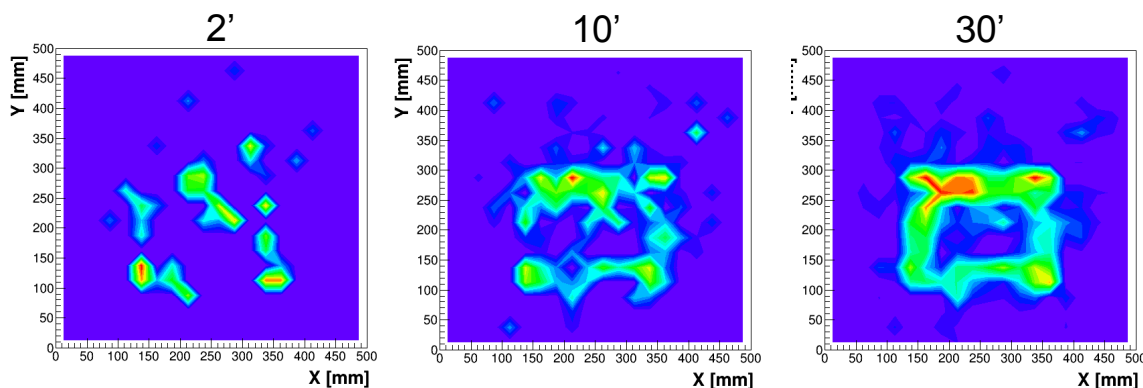
- *Including 1.5 on battery + solar boards*



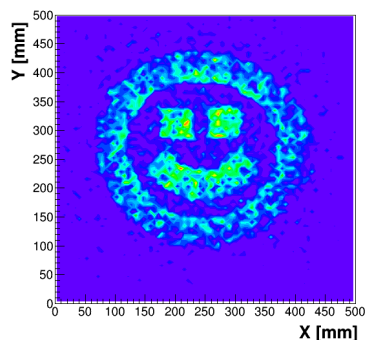
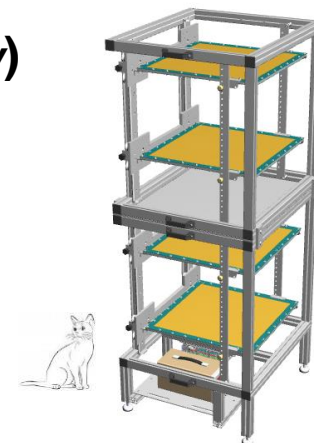
S. Bouteille, S. Procureur et al. Large resistive 2D Micromegas with genetic multiplexing ...

Small setup for communication purpose (*La Diagonale Paris-Saclay*)

→ 4 MG2D-v2 detectors



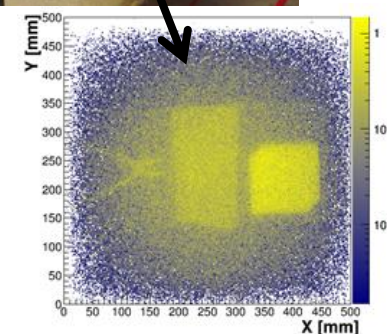
Lead Square



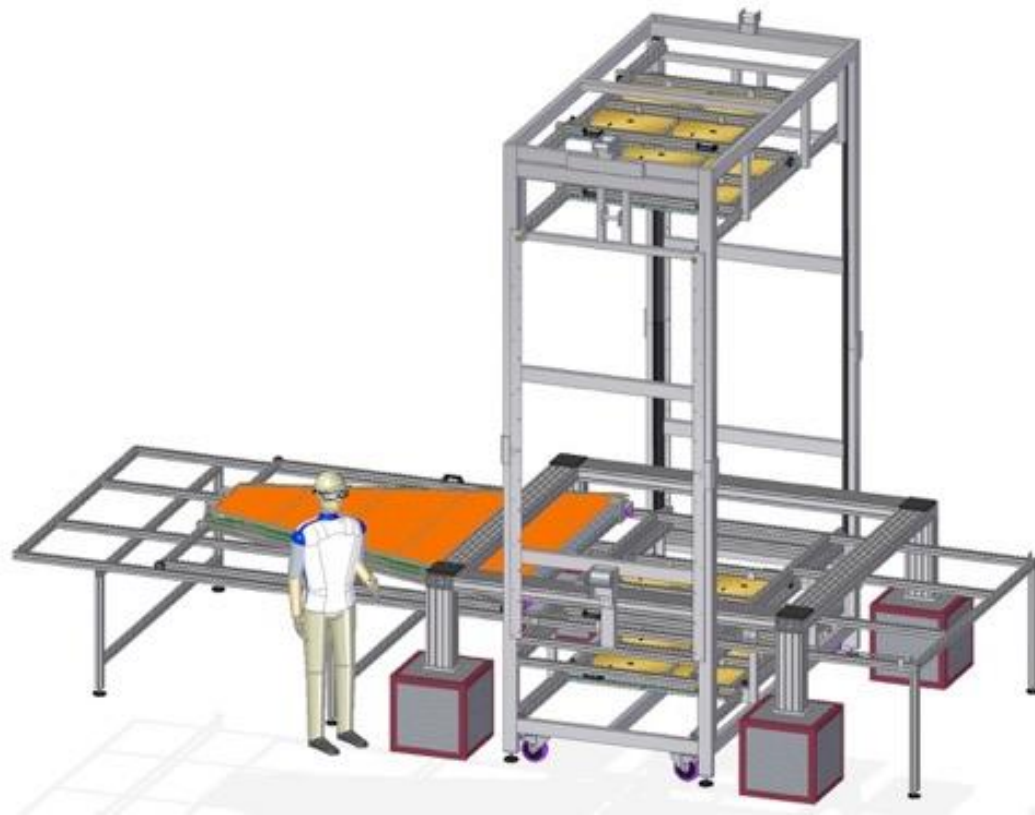
« *Muona Lisa* »

→ Can be used as a transportable scanner for in situ imaging:

⇒ ***Instrument unique in the world, benefit from excellent resolution of MM***



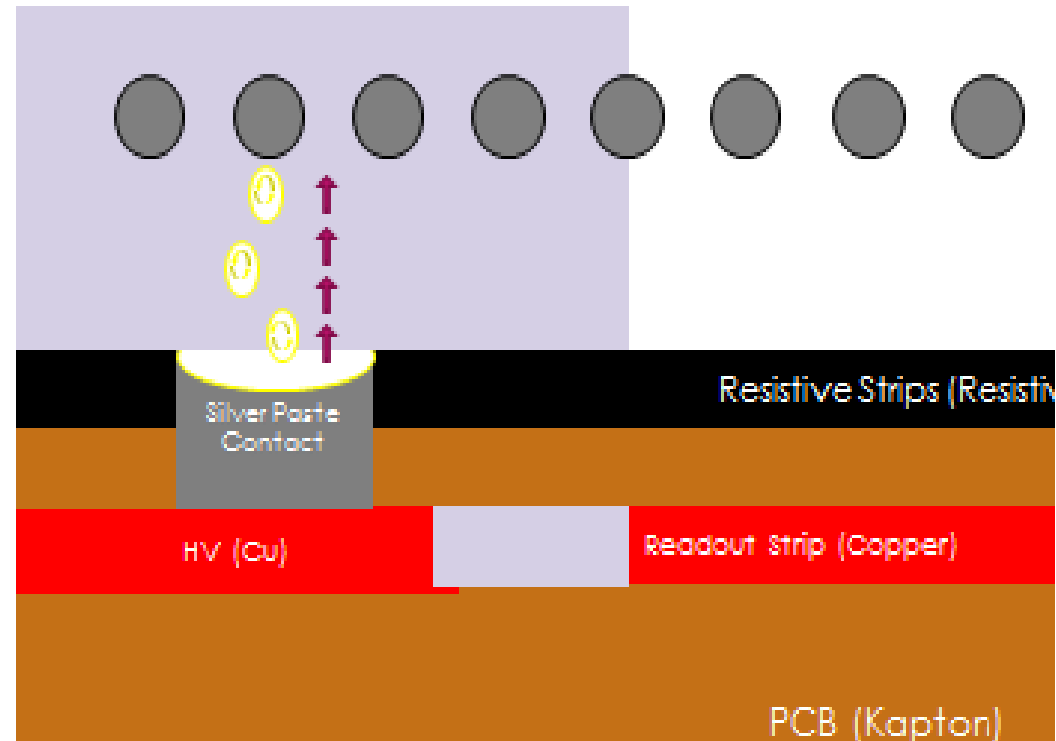
S. Bouteille, S. Procureur et al. A Micromegas-based telescope for muon tomography: the WatTo experiment



- full test to obtain a gain homogeneity and efficiency map, identify dead channels and noisy channels
- Use of cosmic bench made out of Micromegas multiplexed detectors for the M3 projet at Saclay
- 12 Micromegas detectors (0.5 x 0.5 m²) with DREAM electronics
- Scan LM1 module in 5 steps with DREAM electronics

Why the bubbles ?

- ▶ Rui's explanation :
 - ▶ The Silver paste hole is not fully filled
 - ▶ Outgassing of the silver paste filled the hole
 - ▶ With HV, a corona effect starts in the hole
 - ▶ Bubbles starts migrating through the photoresist
 - ▶ This creates the short between mesh (ground) and the resistive layer (HV)



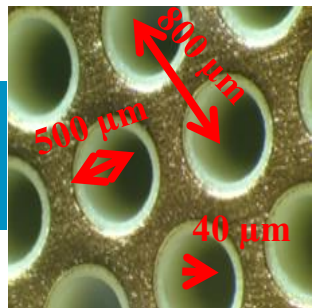
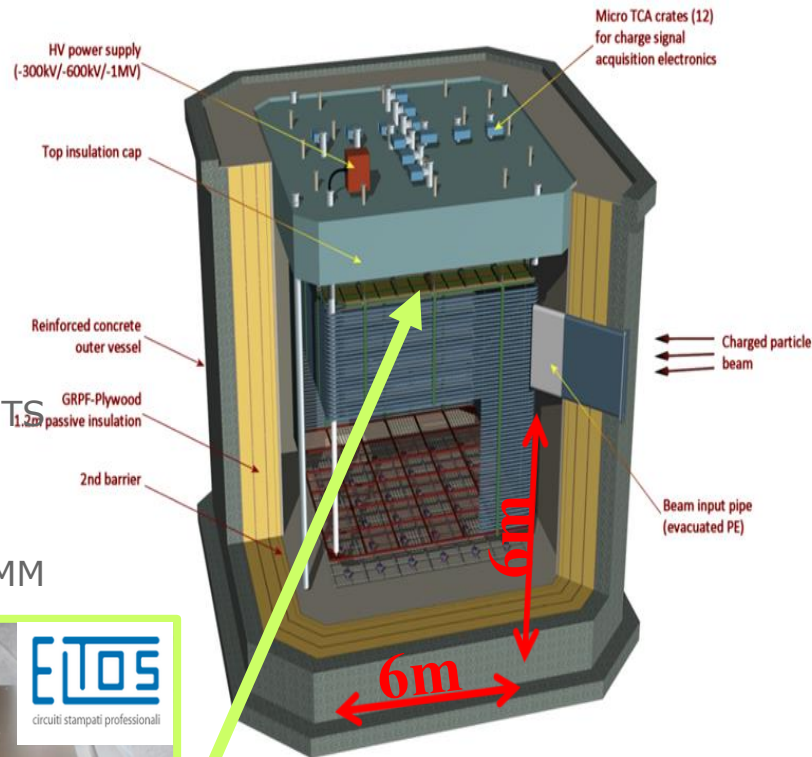
▪ 300T FIDUCIAL MASS ($6 \times 6 \times 6 \text{ m}^3$) TPC OPERATING IN DUAL PHASE LIQUID ARGON (DLAR)

▪ AIM TO DEMONSTRATE THE SCALABILITY OF THE DLAR TECHNIQUE TO $\sim 10 \text{ KT}$ DETECTORS FOR THE FUTURE NEUTRINO PROGRAMME DUvE IN U.S.A. (~ 2025)

▪ WA105 : 36 m^2 READOUT PLANE INSTRUMENTED WITH 144 MPGDs OF LEM (LARGE ELECTRON MULTIPLIER) TYPE

▪ LEM :

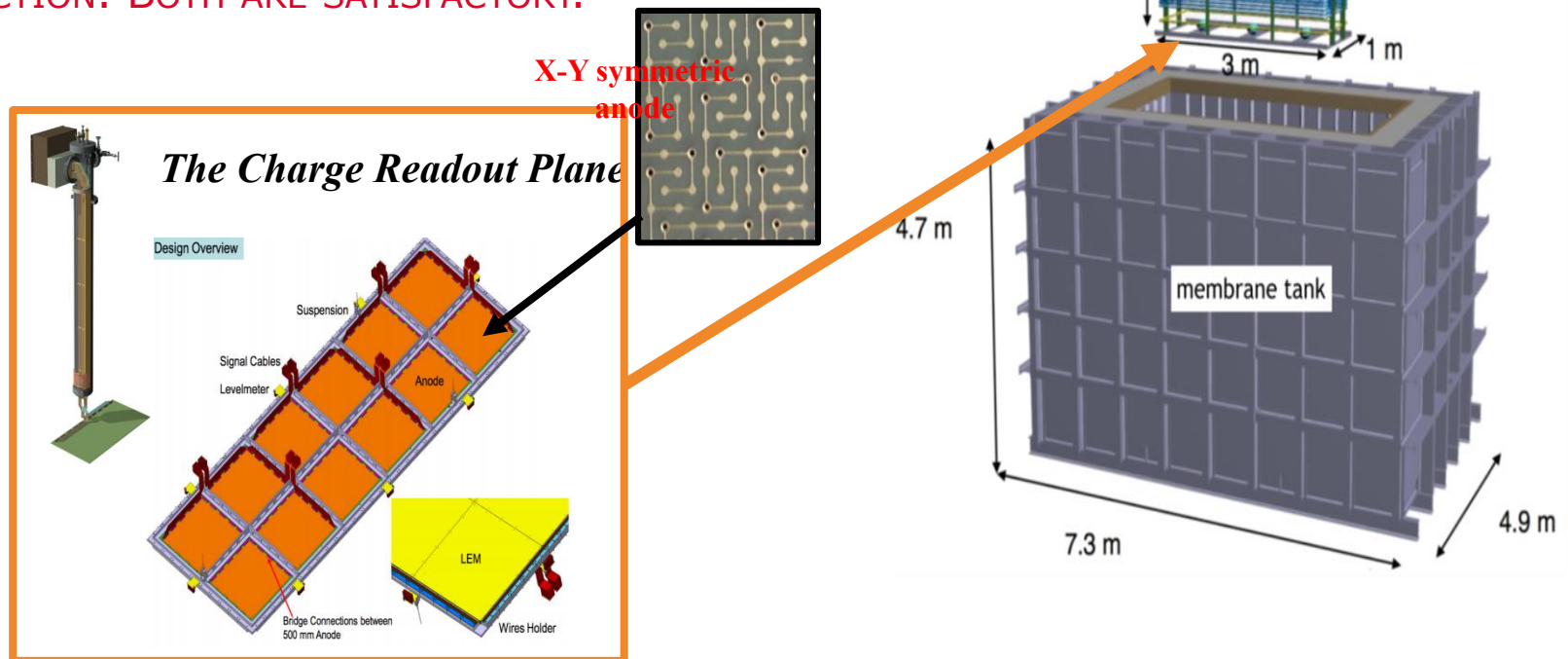
- 1MM THICK FR4 SUBSTRATE WITH THIN COPPER SHEETS ON BOTH SIDES
- $50 \times 50 \text{ cm}^2$ ACTIVE AREA
- AMPLIFICATION THROUGH $\phi = 500 \text{ mm}$ HOLES (800 MM PITCH)
- 40 MM RIM
- READ OUT BY CHARGE COLLECTION WITH A 2D ANODE



$E_{LEM} > 30 \text{ kV/cm}$
in pure Ar @ 87°K

The WA105 DLAr demonstrator

- THE 3M³ PROTOTYPE IS BEING ASSEMBLED IN BLDG. 182 AT CERN
- AIM TO VALIDATE THE TECHNICAL SOLUTIONS FOR THE 300T WA105 DEMONSTRATOR (UNDER CONSTRUCTION AT PREVESSIN)
- COMMISSIONING DELAYED BY INSULATION DEFECT
- NOW ELTOS AND ELVIA INVOLVED IN A PRE-PRODUCTION. BOTH ARE SATISFACTORY.



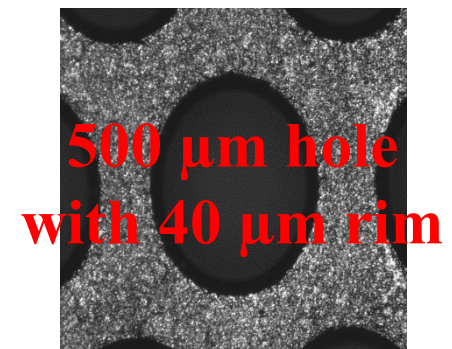
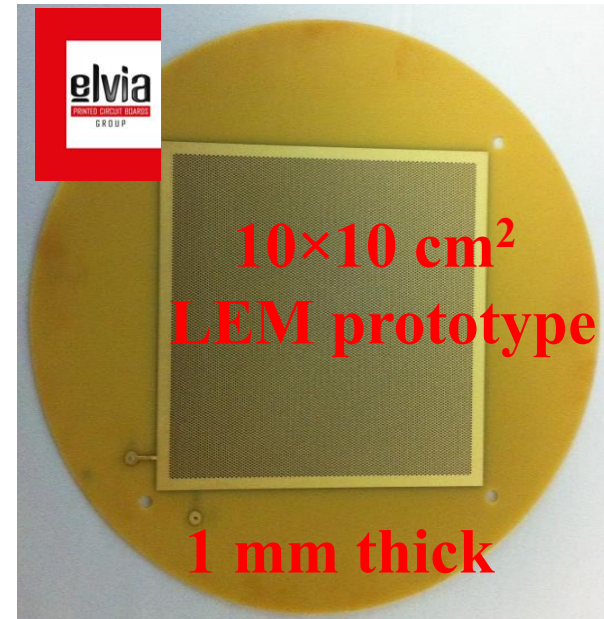
■ STARTED IN FEBRUARY 2016 A PARTNERSHIP WITH ELVIA (FRANCE) IN VIEW OF THE FUTURE LEM PRODUCTION FOR THE WA105 DEMONSTRATOR :

- LEM SPECIFICATIONS, TOLERANCES AND CONSTRUCTION PROCESS (DRILLING, DESMEARING, POLISHING, ...)
- VISIT BY IRFU OF THE PRODUCTION SITE IN COUTANCES (MAY 2016)

■ FIRST PRODUCTION OF SMALL ($10 \times 10 \text{ cm}^2$) LEM PROTOTYPES (APRIL 2016):

- GEOMETRY QUALITY (PCB THICKNESS, SIZE OF HOLES AND RIMS, ...) IS OK
- HV TESTS IN AIR OK (UP TO 3.5 - 4.0kV)
- GAIN MEASUREMENTS WITH α SOURCE IN ARGON @NTP

■ THEN $50 \times 50 \text{ cm}^2$ LEM SAMPLES HAVE BEEN PRODUCED BY ELVIA

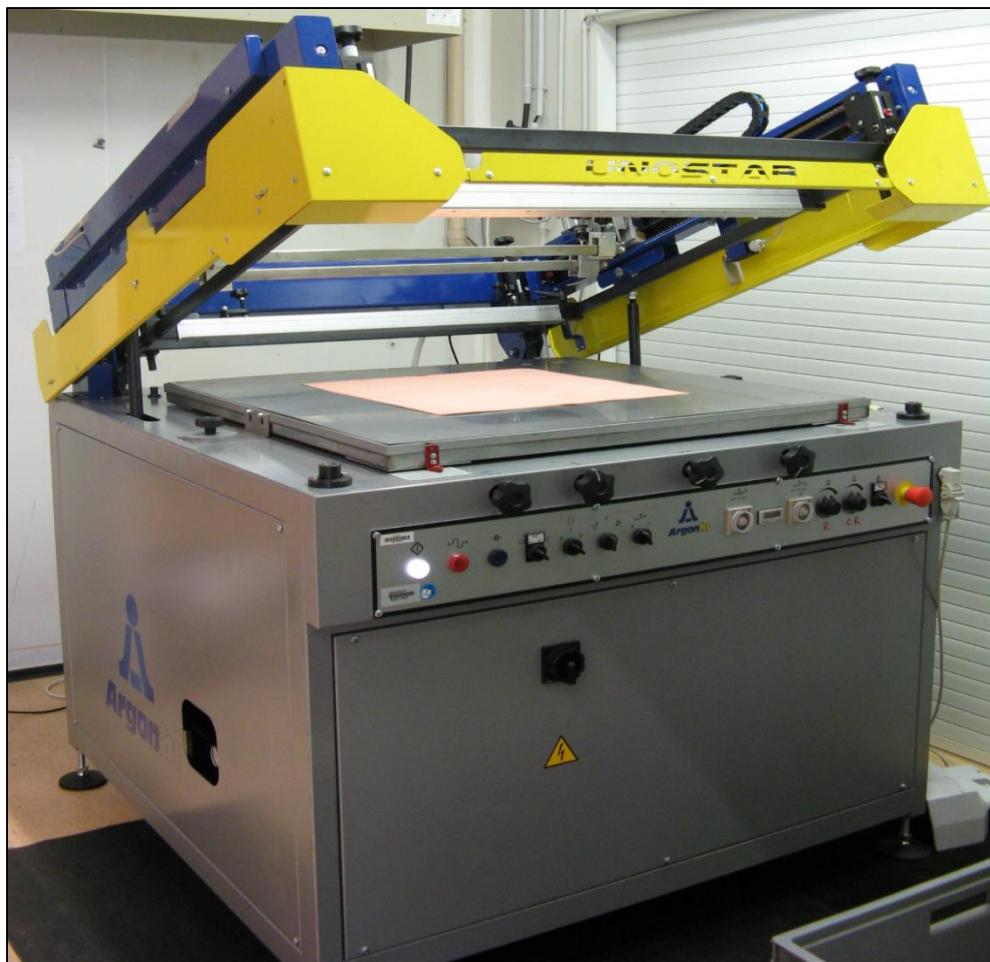


RESISTIVE ANODE STABILIZES MICROMEASUREMENTS AND ALLOWS A CHARGE SPREADING NECESSARY TO IMPROVE RESOLUTION OF MICROMEASUREMENTS

CAN BE APPLIED TO OTHER MPGDs BUT NECESSARY FOR MICROMEASUREMENTS

MANY OPEN WAYS TO BE EXPLORED TO APPLY THE RESISTIVE MATERIAL: SCREEN PRINTING, SPUTTERING, PAINTING, FILM LAMINATION, ETC...

SEVERAL TECHNIQUES ARE USED AND DEVELOPED TO MEASURE SURFACE RESISTIVITY OF A COVERLAY.



SCREEN PRINTING MACHINE
USED ON VARIOUS MATERIALS
(GLASS, KAPTON,...) WITH
VARIOUS INKS AND VARIOUS
PATTERNS (UNIFORM, STRIPS)

PROTOCOLS HAVE BEEN
DEVELOPPED (CURING
TEMPERATURE, CURING TIME,
UNIFORMITY TEST,...)

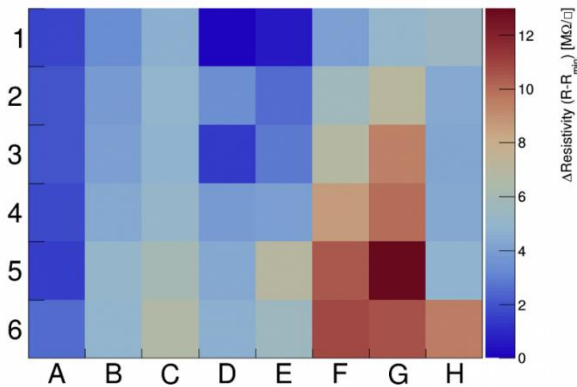
TOOLS HAVE BEEN DESIGNED
OR ACQUIRED (RESISTIVITY
MEASUREMENT, ALIGNMENT)

THE BI COMPONENT PASTE (ELECTRODAG 6017SS + PM-404TM) RESISTIVITY CAN BE ADJUSTED.

UNIFORMITY TEST

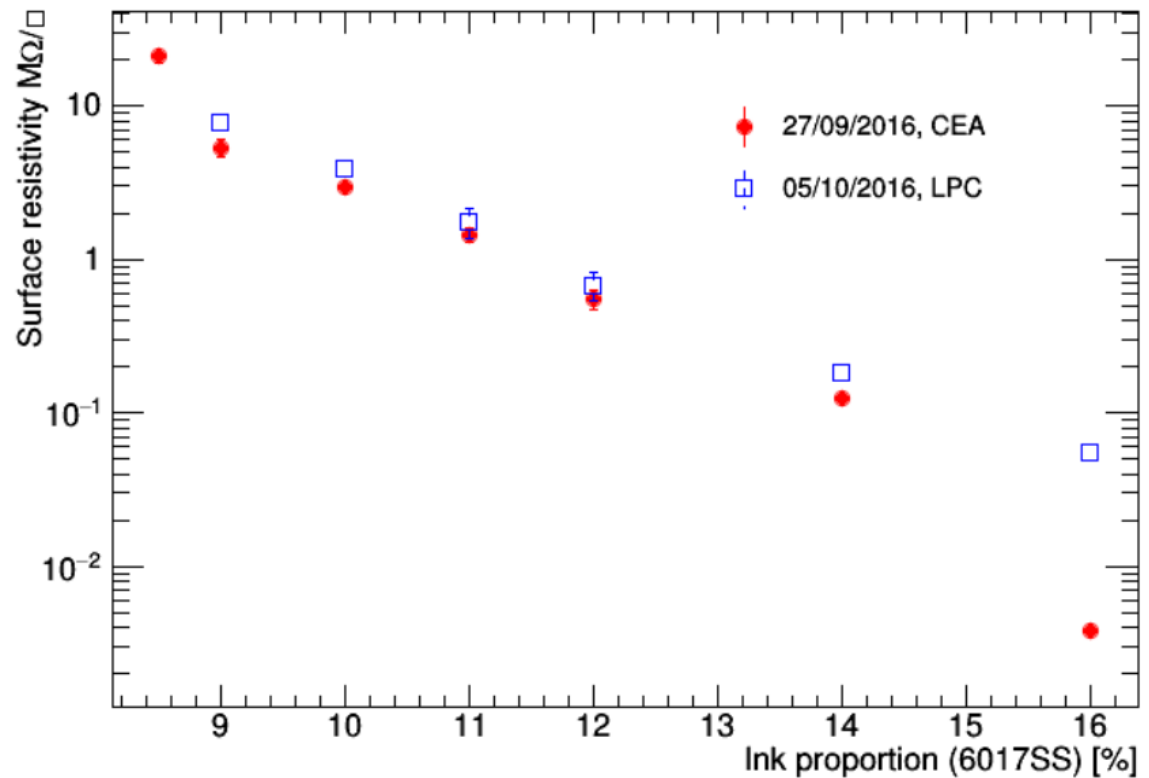
resistivite_17v1rsamerange.png

Standard glass 17 V1



Date: 2016/10/06 12:58

Nom de fichier: resistivite_17v1rsamerange.png



S. AUNE AND C. CARLOGENU MEASURING THE RESISTIVITY WITH A CIRCULAR PROBE IN THE BULK LAB AT SACLAY



Total Spending after 24 months : 32600 euro out of 95000 and 8.3 person.months out of 15.

Several techniques being developed, experience of transfer to industry gained and monitored, very positive results: full large resistive and standard detectors under construction **IN INDUSTRY**

ELVIA and ELTOS are involved in Micromegas (NSW) and LEMs/THGEMs (WA105). Other large Micromegas for Muography. Resistive techniques are developed for muography (volcanos, pyramids)

Thanks to S. Aune, D. Attié, A. Delbart, F. Jeanneau, M. Kebbiri, E. Mazzucato and Nathalie Laurion

BACKUP

PROJECT LEADER : STEPHAN AUNE

BENEFICIARY : CEA

NET EU CONTRIBUTION : 65 k€

MILESTONES (INTERNAL) : PURCHASE OF MATERIAL, SCREEN DESIGN, SCREEN PRINTING TESTS (M12), RESISTIVITY MEASUREMENT TECHNIQUES, TOOL DESIGN AND PURCHASE (M24); REDACTION OF THE PROTOCOL. REPORTS IN RD51.

DELIVERABLE : RESISTIVE ANODE MANUFACTURING
(PROTOCOLS AND TOOLS FOR THE LARGE-SIZE AND LARGE-SCALE PRODUCTION OF RESISTIVE ANODES FOR MICROMEAS)

PROJECT LEADER : FABIEN JEANNEAU

BENEFICIARY : CEA

OTHER CONTRIBUTORS : CERN, ...

NET EU CONTRIBUTION : 35 k€

MILESTONES: PROTOCOL AND SPECIFICATIONS FOR MPGD
PRODUCTION AND QUALITY CONTROL (M36)

INTERNAL MILESTONES: ORDERS OF DETECTOR SERIES TO AT
LEAST TWO PCB COMPANIES (M8) CHARACTERIZATION AND
TESTS AND ITERATIONS.

DELIVERABLE. REPORT ON WORKING DETECTORS.